

SMZ1000

Nikon® **SMZ1000**

- Large 10:1 zoom ratio
- High performance optics
- Ergonomically advanced
- Exceptionally broad accessory lineup
- Available OCC, Nikon's exclusive contrast technique for stereo microscopes

Stereoscopic Zoom Microscope





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Stereoscopic Zoom Microscope

An advanced stereo optical system with features never before thought possible in a microscope of this type

Superior Optics

The SMZ1000 produces brilliant true to life images that are virtually undistorted. There are a total of eight objectives available for the SMZ1000, one to meet every application. For better correction of chromatic aberration, choose an apochromat lens. For long working distance, choose a 0.5x lens.

Superior Ergonomics

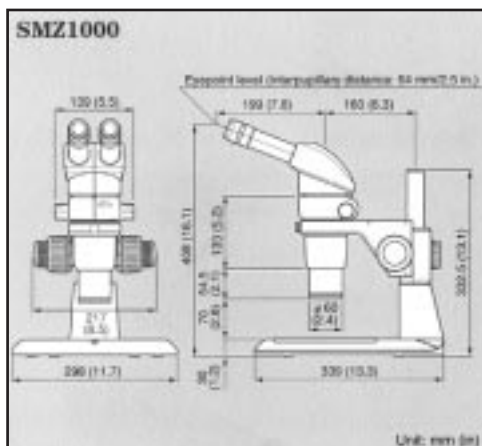
The standard eyepiece tube is inclined 20 degrees to enable the operator to make observations without leaning forward. This minimizes neck fatigue and ensures comfortable operation even after hours of continued use. Other ergonomic features include a patented anti back-lash focusing mechanism that makes fine adjustment of focus easier and more accurate. Also available is up front fine focus, a patented design in which the operator can make fine focus adjustments without removing his/her hand from the specimen.

Expanded Accessory Lineup

One of the keys to a powerful microscope is versatility. That's why the new SMZ1000 comes with a greatly expanded accessory lineup. This lineup includes three new diascopic stands each equipped with up front fine focus and specially designed power supplies that keep temperatures at a low level. This creates an environment ideal for living specimens that are sensitive to temperature.

Oblique Coherent Contrast (OCC)

Nikon has introduced Oblique Coherent Contrast (option), a unique illumination technique designed to make observation of low contrast or transparent samples much easier. In the past, a compound microscope equipped with phase contrast or differential interference contrast was required to see colorless biological specimens. But with OCC, viewing such specimens is now possible through a stereo microscope. OCC can reveal phase differences as small as 1/30 of a wavelength of light.



Specifications

Optical system	Parallel-optics zoom system
Total magnification	4X to 480X depending on eyepiece and objective used. (6X to 540X when coaxial episcopic illuminator is attached)
Eyepiece tubes	P-BT Standard Binocular, Low Eye-level Binocular, P-BERG Tilting Binocular
Eyepiece inclination	20°(Standard Binocular and Low Eye-level Binocular) 0-30°(Tilting Binocular)
Interpupillary distance adjustment	48-75mm (1.9-3.0 in.)
Eyepiece (with diopter adjustment)	C-W10X (F.N. 22), C-W15X (F.N. 16), C-W20X (F.N. 12.5), C-W30X (F.N. 7)
Zooming range	0.8X to 8.0X
Zooming ratio	10 : 1
Objectives	P-Plan Apo 0.5X, 1X ^o , P-ED Plan 1.5X, 2X; P-Plan 1X*; P-Achro 0.5X; P-ERGO Plan 1X ERGO* *Usable at zoom magnifications larger than 1X when mounted on SMZ1000.
Illumination systems	P-ICI2 Coaxial Episcopic Illuminator (12V-100W halogen) Intermediate Magnification is 1.5X. P-FLA FL Epi Fluorescence attachment G-LS 6V-10W Illuminator G-LS 6V-10W Illuminator (with Articulated Arm or G-EIA Articulated Supporting Arm) C-DSLS 6V-20W Illuminator (with Articulated Arm) C-NI-150 Light Source with Heat Filter C-Dual Gooseneck Light pipes C-Single Gooseneck Light Pipes C-Ringlight A C-Ringlight B C-Flourescent Ringlight
Stands	C-PS Plain Focusing Stand C-PSC Compact Plain Focusing Stand C-DS Diascopic Stand S C-PS160 Plain Stand C-DSS Diascopic Stand C-DSD Diascopic Stand C-BD Diascopic Bright/Darkfield Stand P-THS Teaching Head Stand Large Stage Stand
Focusing mount	C-FMC Focusing Mount, C-FMA Focusing Mount A, C-FMB Focusing Mount B
Photomicrographic/CCTV	Nikon Photomicrographic System FX-III Series or CCTV camera can be attached through Beam Splitter and Adapter.

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Specifications and equipment are subject to change without any notice or obligation on the part of the manufacturer.
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